

ASMEX.186DV1



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#141EDS  
5/20/03  
PATENT  
Junker

Applicant : Raaijmakers et al.  
App. No. : 09/764,711  
Filed : January 18, 2001  
For : METHOD OF DEPOSITING  
SILICON WITH HIGH STEP  
COVERAGE  
Examiner : A. Roman

Group Art Unit 2812

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INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing one reference that is also enclosed. This Information Disclosure Statement is being filed before the mailing date of a final action under 37 C.F.R. § 1.113 and before the mailing date of a Notice of Allowance under § 1.311. A certification under 37 C.F.R. § 1.97(e) is set forth below. Thus, no fee is required as set forth in 37 C.F.R. § 1.97(c).

CERTIFICATION UNDER 37 C.F.R. § 1.97(e)(2)

I hereby certify that no item of information contained in this Statement was cited in a communication from a foreign Patent Office in a counterpart foreign application, or, to my knowledge after making reasonable inquiry, was known to any individual designated in 37 C.F.R. § 1.56(c) more than three months days/months prior to the filing of this Information

Appl. No.: 09/764,711  
Filed : January 18, 2001

Disclosure Statement.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: May 8, 2003

By: Adeel S. Akhtar

Adeel S. Akhtar  
Registration No. 41,394  
Attorney of Record  
Customer No. 20,995  
(415) 954-4114

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